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Selective copper metallization of nonconductive materials using jet-circulating electrodeposition

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³ Samsung electronics Co., Ltd., 1-1 Samsungjeonja-ro, Hwaseong-si, Gyeonggi-do, 18448, Korea HighlightsCopper pattern metallization using jet-circulating electrodeposition is proposed.

- Selective metal patterning can be achieved via jet-circulating electrodeposition process.
- Pulse-reverse electrodeposition technique should be applied for high deposition rate.
- Electrolyte jetting condition should be controlled during deposition process.

Abstract

In this paper, a novel selective copper metallization technique that can be used on various materials, such as glass, plastic and ceramic, is proposed. The process consists of three steps: seed layer development, pattern fabrication using jet-circulating electrodeposition, and seed layer removal. A copper seed layer for electrodeposition was formed on various materials by electron beam evaporation. Jet-circulating electrodeposition was implemented to fabricate micro-metal patterns. Localizing the circulation of a jetted electrolyte through two concentric nozzles enables rapid selective electrodeposition. The geometry of the copper pattern was investigated by means of scanning electron microscopy (SEM) and a surface profiler. As a result, copper pattern in various shapes was fabricated. The usage of an outer diameter of 290 µm electrode nozzle, results in a copper pattern with a width of 430 µm and a height of 28 µm. Parameter study of the jet-circulating electrodeposition condition to investigate the electrodeposition mode, electrolyte jetting pressure, and

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